

\$37.39

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Date March 24, 2004

In re the Application of

Takua NAKAMURA

Application No.: 10/080,712

Filed: February 25, 2002

For: METHOD FOR ASSESSING IRRADIATION INTENSITY OF A LASER BEAM, AN APPARATUS FOR ASSESSING IRRADIATION INTENSITY USED UNDER THIS METHOD, AND A LASER BEAM IRRADIATION SYSTEM



Group Art Unit: 3739

Examiner: David M. Shay

Docket No.: 111856

**LARGE ENTITY PETITION FOR 1<sup>st</sup> - 3<sup>rd</sup> EXTENSION  
OF TIME UNDER 37 C.F.R. §1.136(a) AND  
TRANSMITTAL OF FEE UNDER 37 C.F.R. §1.17**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Transmitted herewith is a response to the outstanding Official Action in the above-identified patent application. The shortened statutory period having expired December 24, 2003, an extension of time for a period of 3 months is hereby requested. Attached hereto is our Check No. 152449 in the amount of \$950.00 in payment for:

- Extension fee for response within first month pursuant to §1.136(a) (\$110.00)  
 Extension fee for response within second month pursuant to §1.136(a) (\$420.00)  
 XX Extension fee for response within third month pursuant to §1.136(a) (\$950.00)

The Commissioner is hereby authorized to charge any additional fee or credit any overpayment associated with this communication to Deposit Account No. 15-0461. Two copies of this petition are enclosed.

**RECEIVED**

MAR 29 2004

TECHNOLOGY CENTER R3700

JAO:YSC/dmw

OLIFF & BERRIDGE, PLC  
P.O. Box 19928  
Alexandria, Virginia 22320  
Telephone: (703) 836-6400

03/25/2004 AMB#11  
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00000050 10080712

Respectfully submitted,

James A. Oliff  
Registration No. 27,075

Yong S. Choi  
Registration No. 43,324

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